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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Fujikawa et al.
Serial No.: 10/795,788
Conf. No.: 7705
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For: EXPOSURE MASK AND PATTERN
EXPOSURE METHOD
Art Unit: 2872
Examiner: Unassigned

I hereby certify that this paper is being deposited with the United States Postal Service as FIRST-CLASS mail in an envelope addressed to: Mail Stop MISSING PARTS, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this date.

July 12, 2004

Date

F-CLASS.WCM

Appr. February 20, 1998 Attorney for Applicant


Registration No. 29,367**CLAIM FOR PRIORITY**

Mail Stop MISSING PARTS
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicants claim foreign priority benefits under 35 U.S.C. § 119 on the basis of the foreign applications identified below:

Japanese Patent Application No. 2003-075304, filed March 19, 2003
Japanese Patent Application No. 2004-051596, filed February 26, 2004

Certified copies of the priority documents are enclosed.

Respectfully submitted,

GREER, BURNS & CRAIN, LTD.

By



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